

SEMI F15-0308 (Withdrawn 1011) TEST METHOD (SF₆ TRACER GAS) FOR ENCLOSURES HAS BEEN MOVED TO SEMI S6

This Standard was technically approved by the global Environmental Health & Safety Technical Committee. This edition was approved for publication by the global Audits and Reviews Subcommittee on September 12, 2011. Available at www.semiviews.org and www.semi.org in October 2011; originally published in 1993; previously published March 2008

NOTICE: This Document was balloted and approved for withdrawal in 2011.

1 Purpose

1.1 The purpose of this Document is to provide a permanent withdrawal notice for SEMI F15 indicating that the technical content has been superseded by Appendix 2, Test Method for Determining Fugitive Emissions by Using Tracer Gas of SEMI S6.

2 Scope

2.1 The scope of this Document is all of the content of SEMI F15-93 (Reapproved 1104).

NOTICE: SEMI Standards and Safety Guidelines do not purport to address all safety issues associated with their use. It is the responsibility of the users of the documents to establish appropriate safety and health practices, and determine the applicability of regulatory or other limitations prior to use.

3 Referenced Standards and Documents

3.1 SEMI Standards and Safety Guidelines

SEMI S6 — EHS Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment

SEMI F15-93 (Reapproved 1104) — Test Method for Enclosures Using Sulfur Hexafluoride Tracer Gas and Gas Chromatography

NOTICE: Unless otherwise indicated, all documents cited shall be the latest published versions.

4 Test Method

4.1 Use the Test Method described in Appendix 2, Test Method for Determining Fugitive Emissions by Using Tracer Gas of SEMI S6.

Revision Record

NOTICE: The following information is provided to track revisions to this Document. Negative votes may not be cast against this information. Changes can be submitted to SEMI Staff via a Publication Improvement Proposal (PIP) form available from the SEMI Standards Web site.

<i>Cycle</i>	<i>Authorization</i>	<i>Section</i>	<i>Description</i>
0308	Ballot 4494	Entire Document	Replaced previous Document, which defined a test method, with a pointer to the updated method in an Appendix to SEMI S6.

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